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UTILITY PATENT APPLICATION TRANSMITTAL

(Large Entity)

(Only for new nonprovisional applications under 37 CFR 1.53(b))

Docket No.
11675.168.1Total Pages in this Submission
3

TO THE ASSISTANT COMMISSIONER FOR PATENTS

Box Patent Application
Washington, D.C. 20231

Transmitted herewith for filing under 35 U.S.C. 111(a) and 37 C.F.R. 1.53(b) is a new utility patent application for an invention entitled:

SYSTEM FOR TESTING A SEMICONDUCTOR DEVICE

JC511 09/501033 PTO

02/09/00

and invented by:

Leonard E. Mess

If a CONTINUATION APPLICATION, check appropriate box and supply the requisite information:

Continuation Divisional Continuation-in-part (CIP) of prior application No.: 09/123,633

Which is a:

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Enclosed are:

Application Elements

1. Filing fee as calculated and transmitted as described below
2. Specification having Thirty-one (31) pages and including the following:
 - a. Descriptive Title of the Invention
 - b. Cross References to Related Applications (*if applicable*)
 - c. Statement Regarding Federally-sponsored Research/Development (*if applicable*)
 - d. Reference to Microfiche Appendix (*if applicable*)
 - e. Background of the Invention
 - f. Brief Summary of the Invention
 - g. Brief Description of the Drawings (*if drawings filed*)
 - h. Detailed Description
 - i. Claim(s) as Classified Below
 - j. Abstract of the Disclosure

UTILITY PATENT APPLICATION TRANSMITTAL (Large Entity)

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3

Application Elements (Continued)

3. Drawing(s) (when necessary as prescribed by 35 USC 113)
 - a. Formal Number of Sheets Four (4)
 - b. Informal Number of Sheets _____
4. Oath or Declaration
 - a. Newly executed (original or copy) Unexecuted
 - b. Copy from a prior application (37 CFR 1.63(d)) (for continuation/divisional application only)
 - c. With Power of Attorney Without Power of Attorney
 - d. DELETION OF INVENTOR(S)
Signed statement attached deleting inventor(s) named in the prior application, see 37 C.F.R. 1.63(d)(2) and 1.33(b).
5. Incorporation By Reference (usable if Box 4b is checked)
The entire disclosure of the prior application, from which a copy of the oath or declaration is supplied under Box 4b, is considered as being part of the disclosure of the accompanying application and is hereby incorporated by reference therein.
6. Computer Program in Microfiche (Appendix)
7. Nucleotide and/or Amino Acid Sequence Submission (if applicable, all must be included)
 - a. Paper Copy
 - b. Computer Readable Copy (identical to computer copy)
 - c. Statement Verifying Identical Paper and Computer Readable Copy

Accompanying Application Parts

8. Assignment Papers (cover sheet & document(s))
9. 37 CFR 3.73(B) Statement (when there is an assignee)
10. English Translation Document (if applicable)
11. Information Disclosure Statement/PTO-1449 Copies of IDS Citations
12. Preliminary Amendment
13. Acknowledgment postcard
14. Certificate of Mailing

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UTILITY PATENT APPLICATION TRANSMITTAL
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 11675.168.1

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Accompanying Application Parts (Continued)

15. Certified Copy of Priority Document(s) *(if foreign priority is claimed)*

16. Additional Enclosures *(please identify below):*

Associate Power of Attorney
 PrintEFS Form

Fee Calculation and Transmittal

CLAIMS AS FILED

For	#Filed	#Allowed	#Extra	Rate	Fee
Total Claims	60	- 20 =	40	x \$18.00	\$720.00
Indep. Claims	8	- 3 =	5	x \$78.00	\$390.00
Multiple Dependent Claims (check if applicable)					\$0.00
				BASIC FEE	\$760.00
OTHER FEE (specify purpose)					\$0.00
				TOTAL FILING FEE	\$1,870.00

A check in the amount of **\$1,870.00** to cover the filing fee is enclosed.

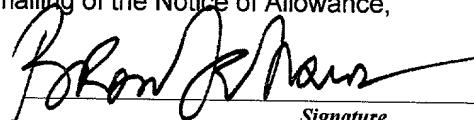
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Charge the issue fee set in 37 C.F.R. 1.18 at the mailing of the Notice of Allowance, pursuant to 37 C.F.R. 1.311(b).



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Dated: February 9 th, 2000

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Invention: **SYSTEM FOR TESTING A SEMICONDUCTOR DEVICE**

I hereby certify that this **Divisional Patent Application and other related documents ***
(Identify type of correspondence)

is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under
37 CFR 1.10 in an envelope addressed to: The Assistant Commissioner for Patents, Washington, D.C. 20231 on
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JoLin Johnson

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* Transmitted: Divisional Patent Application (31 pgs)
Formal Drawings (4 pgs)
Copy of Declaration, Power of Attorney, and Petition (3 pgs)
Copy of Assignment (3 pgs)
Associate Power of Attorney (2 pgs)
PrintEFS Form (2 pgs)
Transmittal Letter (3 pgs)
Certificate of Express Mail Label No. EL446924158US (1 pg)
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APPLICATION INFORMATION

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CONTINUITY INFORMATION

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> Application One:: 09/123,633
Filing Date:: 07-28-1998

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PATENT APPLICATION
Docket No. 11675.168.1

UNITED STATES PATENT APPLICATION

of

LEONARD E. MESS

for

SYSTEM FOR TESTING A SEMICONDUCTOR DEVICE

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A PROFESSIONAL CORPORATION
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1 1. Related Applications.

2 This is a divisional application of US Patent Application Serial No. 09/123,633,
3 filed on July 28, 1998, titled "THERMALLY CONDUCTIVE INTERPOSER AND
4 METHOD" which is incorporated herein by reference.

5

6 **BACKGROUND OF THE INVENTION**7 **2. The Field of the Invention**8 This invention is in the field of semiconductive device technology. More
9 specifically, this invention is in the field of interposers for electrically connecting
10 semiconductive devices to an electrical apparatus.

11

12 **3. The Relevant Technology**13 A semiconductive device is often electrically coupled to an electrical apparatus such
14 as a computer through the use of an interposer. In one such process, the semiconductive
15 device is connected to the interposer, which is then inserted into the socket of the electrical
16 apparatus. The socket may be mounted on the motherboard of a computer, for example.
17 Thus, the semiconductive device communicates electrically through the interposer with the
18 electrical apparatus. Typical interposers currently employed in the coupling of
19 semiconductive devices to electrical apparatuses are comprised of an FR4 fiberglass material,
20 or the like, having electrically conductive metal lines or traces thereon.21 The term "semiconductive device" extends to any device or assembly that includes
22 circuitry defined in a semiconductive material, and further extends to a chip package that
23 includes semiconductive material. The external and additional structure of a package
24 assembly may be used, for example, for mounting the semiconductive device to a printed
25 circuit board or other external circuitry, for establishing electrical connection between the
26 semiconductive device and external circuitry, for improving the ease of handling or

1 transporting the semiconductive device, and/or for protecting the semiconductive device
2 from environmental conditions. Many chip packages include a lead frame that extends
3 beyond the body thereof. The lead frame typically includes an array of electrical leads that
4 extend from the internal circuitry of the integrated circuit to the exterior portion of the chip
5 package where they are exposed to the surroundings.

6 Frequently, after a semiconductive device is manufactured, a testing process is
7 conducted on the semiconductive device by subjecting it to a preselected set of input
8 conditions in order to measure its response or other parameters. Testing of an integrated
9 circuit package that includes a lead frame assembly is conventionally conducted by providing
10 temporary electrical communication between the leads and testing circuitry. For example,
11 such temporary electrical connection may be established by using a set of probes, pins,
12 sockets, or the like, to contact the leads. The integrated circuit package may be clamped or
13 otherwise secured in position during the testing operation in order for the leads to remain in
14 electrical contact with the corresponding probes, pins, sockets, etc., of the testing circuitry.

15 Semiconductive devices, such as DRAMs and SRAMs, undergo significant stresses
16 when in use. Particularly modern, high speed, advanced-integration semiconductive devices
17 generate a significant amount of heat during use. This heat can degrade and slow down
18 semiconductive devices. For example, testing of semiconductive devices to determine the
19 quality and capability of the devices can generate such heat within the devices that the testing
20 process itself damages the devices. Typical fiberglass interposers do not dissipate heat
21 sufficient to protect semiconductive devices from the potential of damage caused by the heat
22 generated during use of the device.

23 In addition, typical fiberglass interposers are made of glass fibers and epoxy resin.
24 The resulting interposer has a coefficient of thermal expansion which is incompatible with
25 typical semiconductive devices. The coefficient of thermal expansion of the fiberglass is
26 often significantly greater than that of the semiconductive device.

1 As a result of this thermal expansion incompatibility, shear stresses develop in the
2 interface between the interposer and the semiconductive device when the semiconductive
3 device becomes hot. These shear stresses can result in a severing of the electrical connection
4 between the interposer and the semiconductive device. While it is possible to ameliorate the
5 effects of shearing through a process known as wire bonding, this process adds additional
6 complexity and expense. Furthermore, the organic material within FR4 fiberglass interposers
7 absorbs moisture, causing the interposers to degrade.

8 There is therefore a need in the art for an improved interposer which assists in
9 protecting a semiconductive device coupled to the interposer from the potential damage
10 caused by significant amounts of heat generated by the semiconductive device. There is also
11 a need in the art for an improved interposer which prevents shear stress from severing the
12 electrical connection between the interposer and the semiconductive device.

1

SUMMARY OF THE INVENTION

2 An interposer of the present invention is comprised of (i) a substrate comprised of
3 an electrically insulating, thermally conductive ceramic material; and (ii) an electrical
4 conductor on the substrate having a receiving end for connecting to a semiconductive device
5 and a terminal end for connecting to an electrical apparatus. The semiconductive device is
6 electrically coupled to the electrical apparatus when the semiconductive device is connected
7 to the receiving end of the electrical conductor and the terminal end of the electrical
8 conductor is connected to the electrical apparatus. The invention also includes thermally
9 conductive connections between the semiconductive device and an interposer.

10 In one embodiment, a thermally conductive connector connects the semiconductive
11 device, such as an SRAM, DRAM, or integrated circuit device, to the interposer such that
12 a portion of the semiconductive device is exposed to the atmosphere to thereby dissipate heat
13 to the atmosphere. Both the thermally conductive interposer and the thermally conductive
14 connector act as heat sinks to conduct heat from the semiconductive device to the ambient,
15 thereby protecting the semiconductive device from overheating. The interposer preferably
16 has a coefficient of thermal expansion which is substantially similar to the coefficient of
17 thermal expansion of a semiconductive device on the interposer, thereby preventing shearing
18 of the electrical connection between the semiconductive device and the interposer.

19 In one embodiment, the semiconductive device is fastened temporarily and
20 removably to the interposer and the interposer is coupled to an electrical apparatus. In
21 another embodiment, the semiconductive device is permanently coupled to the interposer.
22 As an example of a connector, a biasing clip enables quick and convenient placement and
23 removal of semiconductive devices on the interposer. The interposer may be permanently
24 or removably coupled to the electrical apparatus, depending on the desired application.

1 These and other features of the present invention will become more fully apparent
2 from the following description and appended claims, or may be learned by the practice of the
3 invention as set forth hereinafter.

1

BRIEF DESCRIPTION OF THE DRAWINGS

2 In order that the manner in which the above-recited and other advantages of the
3 invention are obtained, a more particular description of the invention briefly described above
4 will be rendered by reference to specific embodiments thereof which are illustrated in the
5 appended drawings. Understanding that these drawings depict only typical embodiments of
6 the invention and are not therefore to be considered to be limiting of its scope, the invention
7 will be described and explained with additional specificity and detail through the use of the
8 accompanying drawings in which:

9 Figure 1 is a perspective view of an interposer kit of the present invention showing
10 one trace array empty, one trace array having a semiconductive device thereon, and one trace
11 array having a semiconductive device thereon with a biasing connector coupling the
12 semiconductive device to the interposer.

13 Figure 2 is a bottom surface view of a semiconductive device.

14 Figure 3 is a perspective view of a biasing connector of the present invention.

15 Figure 4 is a perspective view of another embodiment of a biasing connector of the
16 present invention.

17 Figure 5 is a perspective view of the interposer kit shown in Figure 1 with an
18 additional biasing connector and semiconductive device placed thereon.

19 Figure 6 is a cross-sectional, cut-away view of the semiconductive device and the
20 interposer shown in Figure 1.

21 Figure 7 is a cross-sectional, cut-away view of another embodiment of a
22 semiconductive device and interposer.

23 Figure 8 is a cross sectional, cut away view of the interposer of Figure 1 having an
24 insulating layer on the intermediate portion of a conductor thereof.

25 Figure 9 is a schematic view of an electrical apparatus shown as receiving the
26 interposer kit shown in Figure 5.

DETAILED DESCRIPTION OF THE PREFERRED EMBODIMENTS

With reference now to Figures 1 and 2, the present invention relates to an interposer system 10 comprising (i) an interposer 12; and (ii) a connector 14 for connecting a semiconductive device 16 to interposer 12. Interposer 12 is configured to electrically couple semiconductive device 16 to an electrical apparatus (not shown in Fig. 1), such as a testing apparatus which monitors, tests or evaluates device 16, by for example storing information on device 16 and retrieving information from device 16.

Interposer 12 is electrically coupled to the electrical connections 17 of device 16, the bottom surface of which is shown in Figure 2, and to electrical connections on an electrical apparatus, thereby electrically coupling semiconductive device 16 to the electrical apparatus. By coupling semiconductive devices 16 on interposer 12, and coupling interposer 12 to the electrical apparatus, the electrical apparatus may perform a variety of functions upon the semiconductive devices, while the semiconductive devices are protected from overheating by the heat dissipating qualities of interposer 12.

Interposer 12 and preferably, connector 14, are thermally conductive. As shown in Figure 1, system 10 preferably exposes semiconductive device 16 partially to the open atmosphere, rather than completely covering devices 16 with a connector, allowing heat to dissipate to the atmosphere directly from semiconductive device 16. In addition, heat is transferred through thermally conductive interposer 12 and connector 14 from semiconductive device 16, then dissipated to the atmosphere. The thermal conductivity of interposer 12 and connector 14, along with the configuration of interposer 12 and connector 14 are significant advantages within the art.

Interposer 12 will now be discussed in additional detail. Interposer 12 is comprised of a substrate 18 and a plurality of electrical conductors 20 on substrate 18. Substrate 18 is comprised of an electrically insulating material. Substrate 18 also conducts heat, thereby dissipating heat away from device 16 connected to substrate 18. When exposed to the high

1 temperatures generated by advanced high density, high integration devices 16, substrate 18
2 does not warp or bow. Substrate 18 has formed thereon electrical conductors 20, such as
3 metal traces. Substrate 18 also preferably has substantially similar thermal expansion
4 properties as semiconductor device 16, such as a substantially similar coefficient of thermal
5 expansion as that of semiconductive device 16. By having substantially similar thermal
6 expansion properties, shear stress is reduced in the physical connections between device 16
7 and interposer 12 so as to prevent a severing of the electrical connection between device 16
8 and interposer 12.

9 In one embodiment, substrate 18 is comprised of a ceramic material, such as an
10 inorganic ceramic material. Examples of ceramic materials used in the production of
11 substrate 18 include glass. Many forms of glass may be used, including glass comprising
12 silicates, silica, silicon oxide, phosphates, or borates, or derivatives thereof. Such glass may
13 be doped with metal, an oxide or other elements, so long as it remains electrically insulative.
14 Glass may be formed by fusing silica with a basic oxide, for example. Borophosphosilicate
15 glass is one example of a material useful for substrate 18. Inorganic forms of glass are
16 preferable. Glass materials often have substantially similar thermal expansion properties as
17 semiconductive devices 16, which are often substantially comprised in the most part of
18 silicon or other semiconductive material.

19 In addition to glass, other ceramics useful in the present invention as substrate 18
20 include alumina, aluminum nitrides, nonmetallic nitrides, nonmetallic carbides, single oxide
21 ceramics, mixed oxide ceramics, and mixtures and derivatives thereof. As used throughout
22 this specification and the appended claims, the term "nonmetallic nitrides" includes boron
23 nitrides, silicon nitrides and other transitional element nitrides. Alumina, for example, may
24 be used alone or in combination with silica or silicates, for example, because alumina resists
25 harsh environments and also dissipates heat.

1 Other examples of ceramics useful in the present invention for substrate 18 include
2 glass ceramics, such as nucleated glass having a nonporous, substantially crystalline
3 structure, devitrified ceramics, or vitro ceramics. In one embodiment, glass ceramics are
4 fine-grained substantially crystalline materials made through controlled crystallization from
5 glass compositions containing nucleating agents. Thus, in one embodiment, substrate 18
6 comprises a material selected from the group consisting of glass, alumina, glass ceramic,
7 aluminum nitride, nonmetallic nitride, nonmetallic carbide, and mixtures and derivatives
8 thereof. Other possible, but less preferred ceramics for substrate 18 include refractories such
9 as steatite and mullite.

10 Glass and other ceramics are preferably provided in a substantially homogeneous
11 form for substrate 18, as opposed to the heterogeneous mixture of fibers and epoxy found in
12 FR4 fiberglass. Glass and other ceramics are also preferably provided in substrate 18 in a
13 substantially planar (i.e., flat) sheet, as shown in Figure 1.

14 As shown in Figure 1, interposer 12 includes a plurality of arrays 22, 24, 26 of
15 electrical conductors 20 thereon. Each electrical conductor 20 has a receiving end 28 for
16 connecting to a corresponding terminal 30 of an electrical conductor 32 on the bottom
17 surface of semiconductive device 16 as shown in Figure 2. Each electrical conductor 20 on
18 substrate 18 further comprises a terminal end 34 for connecting to an electrical apparatus.
19 An intermediate portion 36 of conductor 20 extends between receiving end 28 and terminal
20 end 34 of each conductor 20. The connection of terminal end 34 to the electrical apparatus
21 may be permanent or removable.

22 An interposer of the present invention may comprise a single conductor or a plurality
23 of conductors. The interposer may have a single array of conductors or may have a plurality
24 of arrays, such as arrays 22, 24, 26 as shown in Figure 1. Each array may have as many
25 conductors as needed to electrically couple a particular semiconductive device, such as
26 device 16, to an electrical apparatus. Conductors may have a variety of different

1 configurations any of which are designed to electrically couple a semiconductive device to
2 an electrical apparatus. Heat dissipates to the environment through the conductors and from
3 the conductors through the substrate to the ambient.

4 In one embodiment, the semiconductive device is permanently coupled to the
5 interposer. The semiconductive device may be permanently coupled to the interposer
6 through the use of an adhesive, for example, which is another example of a connector. In an
7 underfilling process, adhesive is placed around the edges of semiconductive device 16
8 mounted on interposer 12, then the adhesive is permitted to wick through capillary action
9 between interposer 12 and semiconductive device 16. This process can be repeated until the
10 desired bond is achieved between interposer 12 and the semiconductive device 16. This
11 underfilling process is often used for flip chips, for example. Preferably, the adhesive is a
12 thermally conductive adhesive, such as a silver-filled epoxy, or a tape having acrylics filled
13 with alumina or aluminum nitride with a matrix in resin. The thermally conductive adhesive
14 enhances heat dissipation away from semiconductive device 16. Adhesives may be applied
15 using a screen printing process, for example.

16 In another embodiment, semiconductive device 16 is removably coupled to
17 interposer 12, such as when it is desired to test device 16 by coupling device 16 to testing
18 apparatus which monitors, tests, and/or evaluates device 16. Preferably, when removability
19 is desired, connectors such as resilient biasing connectors 14 are employed. As shown in
20 Figure 1, biasing connector 14 connects device 16 to interposer 12 such that a substantial
21 portion of device 16 is exposed to the open environment, thereby assisting in dissipating heat
22 from device 16.

23 With reference now to Figures 3, 4, and 5, various embodiments of biasing
24 connectors are demonstrated. As shown in Figure 3, connector 14 comprises a resilient clip
25 having a top plate 38, a bottom plate 40, and an intermediate portion 42 coupling top plate

1 38 to bottom plate 40. Connector 14 may be employed to resiliently, removably bias
2 semiconductive device 16 against interposer 12.

3 Another embodiment of a connector 44 is demonstrated in Figure 4. Connector 44
4 comprises a resilient clip having an upper plate 46, a lower plate 48 and an intermediate
5 portion 50 coupling upper plate 46 to lower plate 48. Each of plates 46, 48 include a bow
6 in the central portion thereof. The bow in plates 46, 48 allowing front ends 52, 54 of clip
7 44 to be readily biased open and closed manually for placement over device 16 and substrate
8 12.

9 As shown in Figure 5, in one embodiment one connector 14 is used for a single
10 semiconductive device 16, whereas in another embodiment a single connector 56 is used to
11 couple a plurality of semiconductive devices 16 to interposer 12. Connector 56 may be in
12 the shape of clip 14, clip 44, or a variety of other clips or other configurations. A variety of
13 different designs of connectors may be employed in the present invention such as other clips,
14 crimps, clamps and a variety of other connectors having shapes and configurations which
15 allow them to resiliently, removably bias semiconductive devices 16 to interposer 12.

16 In a preferred embodiment, heat is also conducted through a thermally conductive
17 connector to the environment. Biasing connectors 14, 44, and 56 are preferably comprised
18 of a resilient, heat dissipating material such as copper, copper alloy, or another metal. The
19 connectors are also insulated from the electrical connections on devices 16, such as by being
20 further comprised of or coated with an electrically insulating material, such as glass or
21 polymer or by being placed on electrically insulating portions of devices 16. The connectors
22 thus resiliently, removably bias semiconductive devices 16 against interposer 12 while
23 simultaneously assisting in dissipating the heat generated by devices 16 in conducting the
24 heat to the atmosphere. These connectors do so in a manner which allows a portion of the
25 device itself to be exposed to the atmosphere, thereby increasing the dissipative qualities of
26 system 10.

1 Connectors 14, 44, 56 dissipate heat because they are in intimate thermal contact
2 with devices 16 and because they are comprised of a thermally conductive material.
3 Connectors 14, 44, 56 and other such connectors may be placed on device 16 manually or
4 automatically. One advantage of such connectors over an underfilling process is that the
5 connectors do not need a delay time in which wicking occurs and they avoid the further delay
6 of repeated applications, as well as delays associated with curing of the adhesive.

7 Connectors 14, 44, 56 or a variety of substantially similar connectors may also be
8 employed to assist in permanently coupling devices 16 to substrate 18, thereby providing
9 heat dissipation. For example, it is possible to employ both an adhesive, such as a thermally
10 conductive adhesive and a connector, such as connector 14, 44, or 56 to permanently couple
11 semiconductive device 16 to interposer 12. This may be accomplished, for example, by
12 placing adhesive between substrate 18 and semiconductive device 16 with a connector 14,
13 44, or 56 to couple both substrate 18 and device 16 together and/or by placing the adhesive
14 between connector 14, 44, or 56 and substrate 18, for example. Adhesive may also be placed
15 between connector 14, 44, or 56 and device 16 so long as the electrical connections between
16 connector 14, 44, or 56 and device 16 are preserved.

17 Conductors 20 may be conventionally formed on substrate 18 by being attached or
18 deposited thereon. For example, a metal can be sputtered onto substrate 18, followed by a
19 patterning process to define conductors 20. Other conventional metallizing or metal line
20 deposition processes can also be used. In one embodiment, substrate 18 is initially etched,
21 after which the etched portion is metallized, by metal deposition and a metal line patterning
22 process. Metal deposition and photolithographic metallization processes may be used to etch
23 fine line widths and to place conductors in dense arrays on substrates to form interposers.

24 As shown in Figure 6, in one embodiment, electrical conductor 20 has a bumped
25 receiving end 28 which projects from the upper surface of substrate 18. In this embodiment,
26 semiconductive device 16 includes a corresponding electrical conductor 32 having a bumped

1 terminal 30 which couples to receiving end 28, thereby forming a connection between bump
2 30 and bump 28 when device 16 and interposer 12 are connected together such that bumps
3 28 and 30 interface. This creates a physical connection between substrate 18 and device 16.
4 This configuration allows bumps 28, 30 to slide against one another, permitting convenient
5 coupling of bumps 28, 30 together as well as removal of bumps 28, 30 one from another.

6 In another embodiment, as shown in Figure 7, the electrical connection between an
7 interposer 59 and a semiconductive device 58 is created by providing for a complimentary,
8 male/female connection between device 58 and interposer 59. Although interposer 59 is
9 shown as comprising the female fitting, the interposer may comprise the male fitting, as
10 shown in Figure 6 with protruding bumped receiving end 28, while the semiconductive
11 device comprises the female fitting which is formed in a recess of the semiconductive device.

12 In the embodiment shown in Figure 7, interposer 59 comprises a substrate 60 having
13 a recess 62 therein. A conductor 64 such as a metal trace is placed on substrate 60 such that
14 a receiving end 66 of conductor 64 is disposed within recess 62, which is below the upper
15 surface of substrate 60, allowing a male connecting terminal 68 of a conductor on
16 semiconductive device 58 to be electrically coupled with receiving end 66 by being placed
17 therein. Conductor 64 also has a terminal end (not shown) for connecting to an electrical
18 apparatus. A connector such as connector 14, 44, or 56 may then be placed to bias device
19 58 towards substrate 60 to thereby retain the electrical connection between bump 68 and
20 recessed receiving end 66. It will be appreciated that the male/female complimentary fit
21 shown in Figure 7 would be advantageous because of the structural integrity and non-slip
22 design derived therefrom.

23 According to one method of manufacturing interposer 12 or 59, a substrate 18 or 60
24 of the present invention is provided comprising a ceramic material. At least one electrical
25 conductor 20 or 64 is then coupled onto the substrate. In one embodiment, recess 62 is
26 formed within substrate 60, such as through etching, and at least a portion of conductor 64

1 is placed within the recess 62. A recess may be formed to receive receiving end 66, as shown
2 in Figure 7, the entire conductor, an intermediate portion of conductor 64 and end 66, or a
3 variety of other portions of conductor 64.

4 As yet another feature of the invention, as shown in Figure 8, it is possible to form
5 a layer 69, such as a coating, of an electrically insulating material on the intermediate
6 portion 36 of electrical conductor 20 of interposer 12. The electrically insulating material
7 for layer 69 may comprise an electrically insulating material, such as a polymer or resin. In
8 one embodiment, the electrically insulating material is thermally conductive, such as a
9 ceramic material such as described above (e.g., glass, aluminum nitride or alumina), for
10 example. Thus, in one embodiment, layer 69 electrically insulates conductor 20 from contact
11 with an electrical conductor, such as an uninsulated connector, and simultaneously aids in
12 heat dissipation.

13 With reference now to Figure 9, interposer 12 having semiconductive devices 16
14 electrically coupled thereto through the use of connectors 14, 56 is electrically coupled to an
15 electrical apparatus 70 such as a testing apparatus shown in a diagrammatic view in Figure 9.
16 Interposer 12 may be permanently or removably coupled to apparatus 70.

17 As used throughout this specification and the appended claims, the term "electrical
18 apparatus" refers to an apparatus which electrically couples to a semiconductive device.
19 Examples of such apparatuses include a computer, program logic controller, electronic game
20 assembly, a controlling module, and a testing apparatus which monitors, tests, or evaluates
21 a semiconductive device. The testing apparatus may be a computerized testing apparatus,
22 for example.

23 Apparatus 70 includes a socket, such as a printed circuit board socket, having
24 electrical terminals onto which terminal ends 34 of conductors 20 of interposer 12 are placed.
25 After terminal ends 34 of interposer 12 are placed into the socket, an electrical connection

1 exists between semiconductive devices 16 and apparatus 70, thereby allowing a user to test
2 device 16 or otherwise engage in a variety of different functions.

3 Thus, one method for testing semiconductive device comprises providing an
4 interposer having substrate comprised of an electrically insulating, thermally conductive
5 ceramic material, electrically coupling the interposed to a semiconductive device, electrically
6 coupling the interposer to a testing apparatus such that the testing apparatus is electrically
7 coupled to semiconductive device, and then actuating the testing apparatus to electrically
8 communicate with the semiconductive device.

9 A variety of different semiconductive devices may be electrically coupled to the
10 inventive interposer. Examples of such semiconductive devices include DRAMs, SRAMs,
11 integrated circuit devices, and the like, each of which has electrical conductors thereon such
12 as bumps, lead fingers, or other package connections. The semiconductive devices, however,
13 may be either packaged or non-packaged.

14 The present invention may be embodied in other specific forms without departing
15 from its spirit or essential characteristics. The described embodiments are to be considered
16 in all respects only as illustrative and not restrictive. The scope of the invention is, therefore,
17 indicated by the appended claims rather than by the foregoing description. All changes
18 which come within the meaning and range of equivalency of the claims are to be embraced
19 within their scope.

20 What is claimed and desired to be secured by United States Letters Patent is:

1 1. A system for electrically coupling a semiconductive device to an electrical
2 apparatus, the system comprising:

3 an interposer, the interposer comprising:

4 a substrate comprised of an electrically insulating ceramic
5 material; and

6 a plurality of electrical conductors on the substrate, each
7 electrical conductor having a receiving end for connecting to a
8 semiconductive device and a terminal end for connecting to an
9 electrical apparatus, such that electrical circuitry within the
10 semiconductive device is electrically coupled to the electrical
11 apparatus when the semiconductive device is connected to said
12 plurality of receiving ends of the electrical conductors and said
13 plurality of terminal ends of the electrical conductors are connected
14 to the electrical apparatus; and

15 a connector for holding the semiconductive device stationary relative to the
16 interposer.

17
18 2. A system as recited in claim 1, wherein the connector connects the
19 semiconductive device to the interposer such that a portion of the semiconductive device is
20 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

21
22 3. A system as recited in claim 1, wherein the connector removably connects the
23 semiconductive device to the interposer.

24
25 4. A system as recited in claim 1, wherein the connector comprises a resilient
26 biasing clip.

1 5. A system as recited in claim 1, wherein the connector is composed of a metal
2 material.

3
4 6. A system as recited in claim 1, wherein the connector comprises an adhesive.

5
6 7. A system as recited in claim 1, wherein at least one of said receiving ends
7 projects from the substrate.

8
9 8. A system as recited in claim 1, wherein at least one of said receiving ends is
10 disposed within a recess in the substrate.

1 9. A system for testing a semiconductive device, the system comprising:
2 an electrical testing apparatus;
3 a semiconductive device having an electrical circuitry therein electrically
4 connected to an electrical lead projecting therefrom;
5 an interposer, the interposer comprising:
6 a substrate comprised of an electrically insulating material
7 selected from the group consisting of glass, alumina, glass ceramic,
8 nonmetallic nitride, aluminum nitride, nonmetallic carbide, and
9 mixtures and derivatives thereof; and
10 an electrical conductor on the substrate, the electrical
11 conductor having a receiving end for connecting to the electrical lead
12 of the semiconductive device and a terminal end for connecting to the
13 electrical testing apparatus, whereby the semiconductive device is
14 electrically coupled to the electrical testing apparatus when the
15 electrical lead of the semiconductive device is in contact with the
16 receiving end of the electrical conductor and the terminal end of the
17 electrical conductor is in electrical communication with the electrical
18 testing apparatus.

19
20 10. The system as defined in Claim 9, further comprising:
21 a connector for biasing the electrical lead of the semiconductive device
22 towards and in contact with the receiving end of the electrical conductor, the
23 connector being composed of copper and alloys thereof.

24
25 11. The system as defined in Claim 10, wherein the connector has a coating
26 thereon composed of an electrically insulating material.

1 12. A system as recited in claim 10, wherein the connector connects the
2 semiconductive device to the interposer such that a portion of the semiconductive device is
3 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

4

5 13. A system as recited in claim 10, wherein the connector removably connects
6 the semiconductive device to the interposer.

7

8 14. A system as recited in claim 10, wherein the connector comprises a resilient
9 biasing clip.

10

11 15. A system as recited in claim 10, wherein the connector is composed of a metal
12 material.

13

14 16. A system as recited in claim 10, wherein the connector comprises an adhesive.

15

16 17. A system as recited in claim 9, wherein at least one of said receiving ends
17 projects from the substrate.

18

19 18. A system as recited in claim 9, wherein at least one of said receiving ends is
20 disposed within a recess in the substrate.

1 19. A system for electrically coupling a semiconductive device to an electrical
2 apparatus, the system comprising:

3 an interposer, the interposer comprising:
4 a substrate comprised of an electrically insulating, ceramic material;
5 and

6 an electrical conductor on the substrate, the electrical conductor
7 having a receiving end for connecting to the semiconductive device and a
8 terminal end for connecting to the electrical apparatus; and
9 a connector for holding the semiconductive device stationary relative to the
10 interposer.

11
12 20. The system as defined in claim 19, wherein the substrate comprises a
13 substantially planar sheet.

14
15 21. The system as defined in claim 19, wherein the substrate comprises a
16 substantially homogenous material.

17
18 22. The system as defined in claim 19, wherein the receiving end protrudes
19 upwardly with respect to the substrate.

20
21 23. The system as defined in claim 19 wherein the receiving end is disposed
22 within a recess in the substrate.

23
24 24. The system as defined in claim 19, wherein the substrate comprises a material
25 selected from the group consisting of glass, alumina, glass ceramic, nonmetallic nitride,
26 aluminum nitride, nonmetallic carbide, and mixtures and derivatives thereof.

1 25. The system as defined in claim 19, wherein the substrate comprises boron
2 nitride.

3
4 26. The system as defined in claim 19, wherein the interposer further comprises
5 an electrically insulating layer on a portion of the conductor between the receiving end and
6 the terminal end.

7
8 27. The system as defined in claim 26, wherein the electrically insulating layer
9 comprises a thermally conductive material.

10
11 28. A system as recited in claim 19, wherein the connector connects the
12 semiconductive device to the interposer such that a portion of the semiconductive device is
13 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

14
15 29. A system as recited in claim 19, wherein the connector removably connects
16 the semiconductive device to the interposer.

17
18 30. A system as recited in claim 19, wherein the connector comprises a resilient
19 biasing clip.

20
21 31. A system as recited in claim 19, wherein the connector is composed of a metal
22 material.

23
24 32. A system as recited in claim 19, wherein the connector comprises an adhesive.

1 33. A system as recited in claim 19, wherein at least one of said receiving ends
2 projects from the substrate.

3
4 34. A system as recited in claim 19, wherein at least one of said receiving ends
5 is disposed within a recess in the substrate.

6
7 35. A system for electrically coupling a semiconductive device to an electrical
8 apparatus, the system comprising:

9 an interposer, the interposer comprising:

10 a substantially homogeneous, substantially planar sheet comprised of
11 an electrically insulating, inorganic ceramic material; and

12 an electrical conductor on the sheet, the electrical conductor having
13 a receiving end for connecting to a semiconductive device and a terminal end
14 for connecting to an electrical apparatus, such that the semiconductive device
15 is electrically coupled to the electrical apparatus when the semiconductive
16 device is connected to the receiving end of the electrical conductor and the
17 terminal end of the electrical conductor is connected to the electrical
18 apparatus; and

19 a connector for holding the semiconductive device stationary relative to the
20 interposer.

21
22 36. The system as recited in claim 35, wherein the substrate consists essentially
23 of alumina.

24
25 37. The system as recited in claim 35, wherein the substrate consists essentially
26 of a glass ceramic material.

1 38. A system as recited in claim 35, wherein the connector connects the
2 semiconductive device to the interposer such that a portion of the semiconductive device is
3 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

4

5 39. A system as recited in claim 35, wherein the connector performs a function
6 selected from the group consisting of:

7 removably connects the semiconductive device to the interposer;
8 resiliently biases the semiconductive device to the interposer; and
9 adhesively connects the semiconductive device to the interposer.

10

11 40. A system as recited in claim 35, wherein at least one of said receiving ends
12 projects from the substrate.

13

14 41. A system as recited in claim 35, wherein at least one of said receiving ends
15 is disposed within a recess in the substrate.

1 42. A system for electrically coupling a semiconductive device to an electrical
2 apparatus, the system comprising:

3 an interposer, the interposer comprising:

4 a substantially homogeneous, substantially planar sheet composed of
5 an electrically insulating material selected from the group consisting of glass
6 ceramics, devitrified ceramics, vitro ceramics, alumina, single oxide
7 ceramics, and mixed oxide ceramics, and mixtures and derivatives thereof;
8 and

9 an electrical conductor on the sheet, the electrical conductor having
10 a receiving end for connecting to the semiconductive device and a terminal
11 end for connecting to the electrical apparatus, such that the semiconductive
12 device is electrically coupled to the electrical apparatus when the
13 semiconductive device is connected to the receiving end of the electrical
14 conductor and the terminal end of the electrical conductor is connected to the
15 electrical apparatus

16 a connector for holding the semiconductive device stationary relative to the
17 interposer.

18
19 43. A system as recited in claim 42, wherein the connector performs a function
20 selected from the group consisting of:

21 removably connects the semiconductive device to the interposer;
22 resiliently biases the semiconductive device to the interposer; and
23 adhesively connects the semiconductive device to the interposer.

24
25 44. A system as recited in claim 42, wherein at least one of said receiving ends
26 projects from the substrate.

1 45. A system as recited in claim 42, wherein at least one of said receiving ends
2 is disposed within a recess in the substrate.

3

4 46. A system as recited in claim 42, wherein the connector connects the
5 semiconductive device to the interposer such that a portion of the semiconductive device is
6 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

7

8 47. A system for electrically coupling a semiconductive device to an electrical
9 apparatus, the system comprising:

10 an interposer, the interposer comprising:

11 a substantially homogeneous, substantially planar sheet composed of
12 an electrically insulating material selected from the group consisting of
13 alumina, alumina with silica, alumina with silicates, alumina with derivatives
14 of silicates, and mixtures and derivatives thereof; and

15 an electrical conductor on the sheet, the electrical conductor having
16 a receiving end for connecting to the semiconductive device and a terminal
17 end for connecting to the electrical apparatus, such that the semiconductive
18 device is electrically coupled to the electrical apparatus when the
19 semiconductive device is connected to the receiving end of the electrical
20 conductor and the terminal end of the electrical conductor is connected to the
21 electrical apparatus

22 a connector for holding the semiconductive device stationary relative to the
23 interposer.

1 48. A system as recited in claim 47, wherein the connector performs a function
2 selected from the group consisting of:

3 removably connects the semiconductive device to the interposer;
4 resiliently biases the semiconductive device to the interposer; and
5 adhesively connects the semiconductive device to the interposer.

6

7 49. A system as recited in claim 47, wherein at least one of said receiving ends
8 projects from the substrate.

9

10 50. A system as recited in claim 47, wherein at least one of said receiving ends
11 is disposed within a recess in the substrate.

12

13 51. A system as recited in claim 47, wherein the connector connects the
14 semiconductive device to the interposer such that a portion of the semiconductive device is
15 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

1 52. A system for electrically coupling a semiconductive device to an electrical
2 apparatus, the system comprising:

3 an interposer, the interposer comprising:

4 a substantially homogeneous, substantially planar sheet composed of
5 an electrically insulating material selected from the group consisting of boron
6 nitrides, aluminum nitrides, and mixtures and derivatives thereof; and

7 an electrical conductor on the sheet, the electrical conductor having
8 a receiving end for connecting to a semiconductive device and a terminal end
9 for connecting to an electrical apparatus, such that the semiconductive device
10 is electrically coupled to the electrical apparatus when the semiconductive
11 device is connected to the receiving end of the electrical conductor and the
12 terminal end of the electrical conductor is connected to the electrical
13 apparatus

14 a connector for holding the semiconductive device stationary relative to the
15 interposer.

16
17 53. A system as recited in claim 52, wherein the connector performs a function
18 selected from the group consisting of:

19 removably connects the semiconductive device to the interposer;
20 resiliently biases the semiconductive device to the interposer; and
21 adhesively connects the semiconductive device to the interposer.

22
23 54. A system as recited in claim 52, wherein at least one of said receiving ends
24 projects from the substrate.

1 55. A system as recited in claim 52, wherein at least one of said receiving ends
2 is disposed within a recess in the substrate.

3

4 56. A system as recited in claim 52, wherein the connector connects the
5 semiconductive device to the interposer such that a portion of the semiconductive device is
6 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

7

8 57. A system for electrically coupling a semiconductive device to an electrical
9 apparatus, the system comprising:

10 an interposer, the interposer comprising:

11 a substantially homogeneous, substantially planar sheet composed of
12 an electrically insulating material selected from the group consisting of
13 oxides of silicon, silicate glass, and nucleated, substantially crystalline glass,
14 and mixtures and derivatives thereof; and

15 an electrical conductor on the sheet, the electrical conductor having
16 a receiving end for connecting to the semiconductive device and a terminal
17 end for connecting to the electrical apparatus, such that the semiconductive
18 device is electrically coupled to the electrical apparatus when the
19 semiconductive device is connected to the receiving end of the electrical
20 conductor and the terminal end of the electrical conductor is connected to the
21 electrical apparatus

22 a connector for holding the semiconductive device stationary relative to the
23 interposer.

1 58. A system as recited in claim 57, wherein the connector performs a function
2 selected from the group consisting of:

3 removably connects the semiconductive device to the interposer;
4 resiliently biases the semiconductive device to the interposer; and
5 adhesively connects the semiconductive device to the interposer.

6

7 59. A system as recited in claim 57, wherein at least one of said receiving ends
8 projects from the substrate.

9

10 60. A system as recited in claim 57, wherein at least one of said receiving ends
11 is disposed within a recess in the substrate.

12

13 61. A system as recited in claim 57, wherein the connector connects the
14 semiconductive device to the interposer such that a portion of the semiconductive device is
15 exposed to the atmosphere to thereby dissipate heat to the atmosphere.

1

ABSTRACT OF THE INVENTION

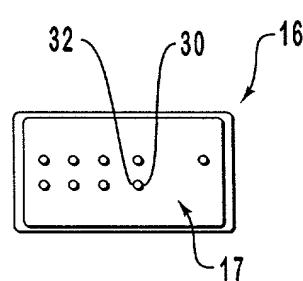
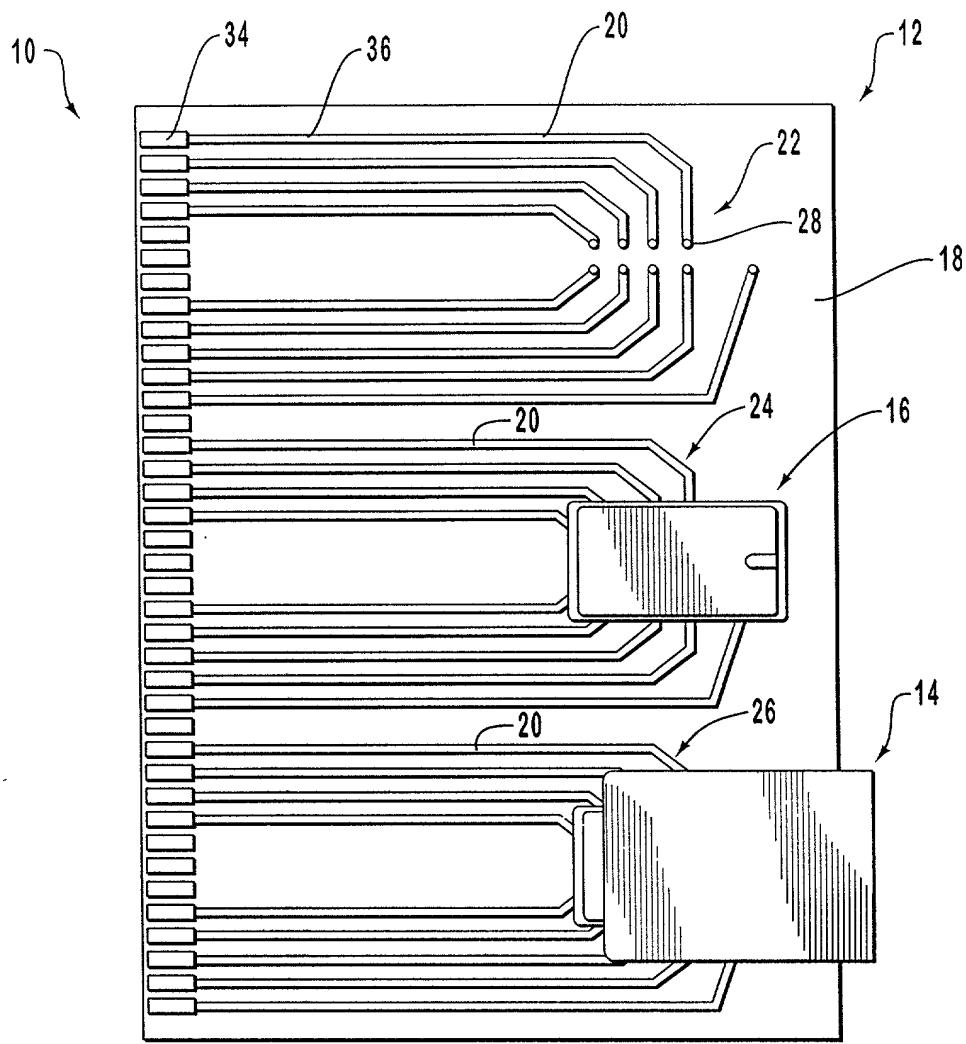
2

A system including an interposer and a coupler for electrically coupling a
3 semiconductive device to an electrical apparatus. The system also includes (i) a substrate
4 comprised of an electrically insulating, thermally conductive ceramic material; and (ii) an
5 electrical conductor on the substrate having a receiving end for connecting to a
6 semiconductive device and a terminal end for connecting to an electrical apparatus. The
7 semiconductive device is electrically coupled to the electrical apparatus when the
8 semiconductive device is connected to the receiving end of the electrical conductor and the
9 terminal end of the electrical conductor is connected to the electrical apparatus. A thermally
10 conductive coupler or connector connects the semiconductive device to the interposer. The
11 thermally conductive interposer and connector conduct heat from the semiconductive device
12 to the environment, thereby protecting the semiconductive device from overheating.

13

14

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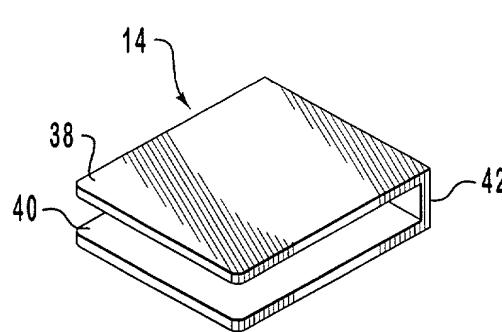


FIG. 3

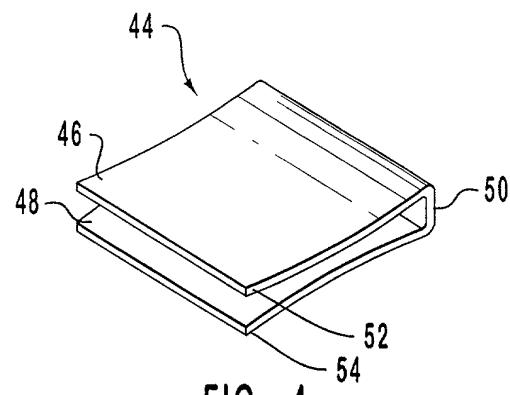


FIG. 4

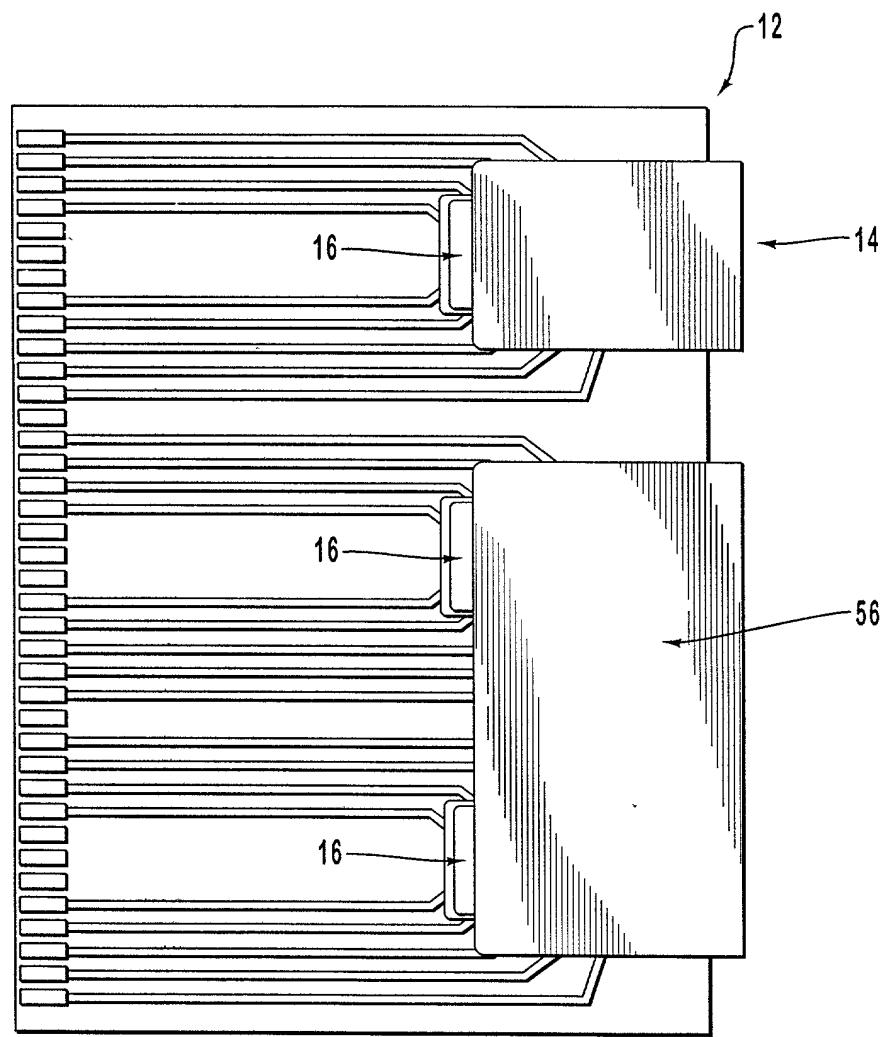


FIG. 5

3 / 4

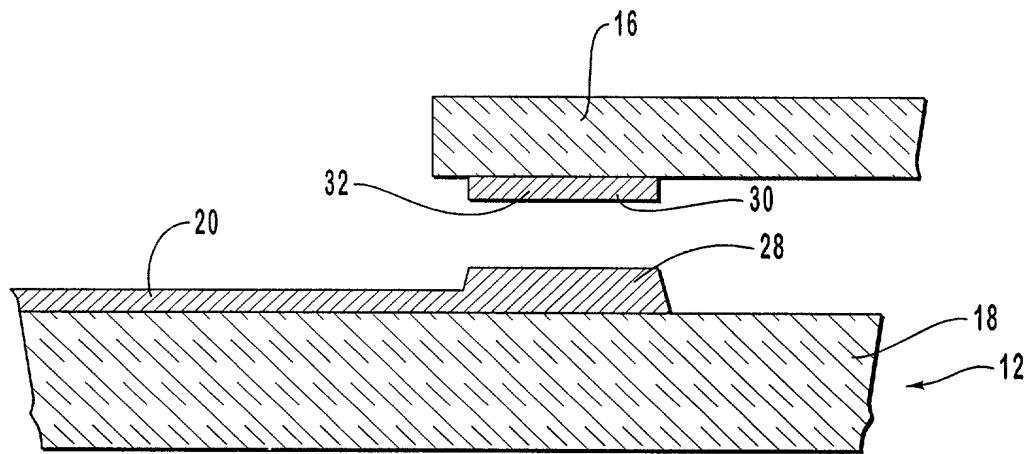


FIG. 6

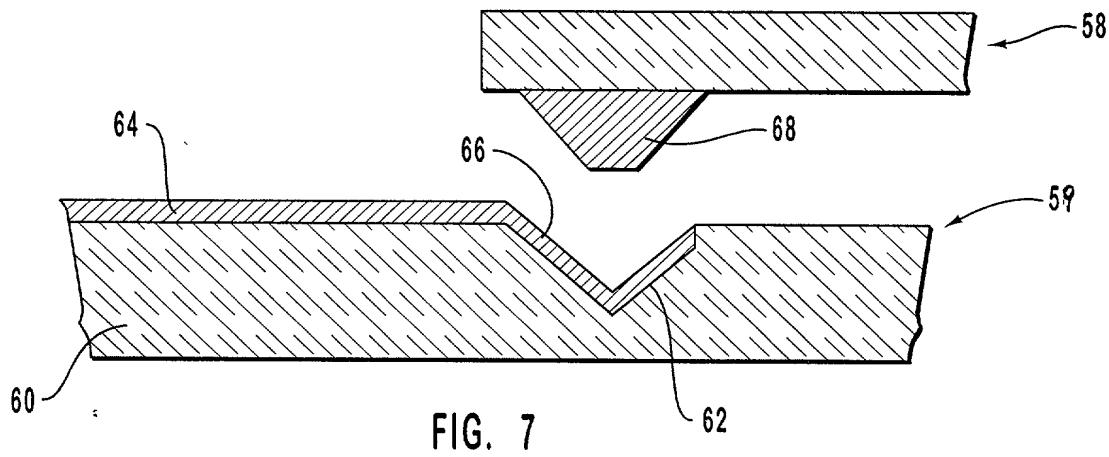


FIG. 7

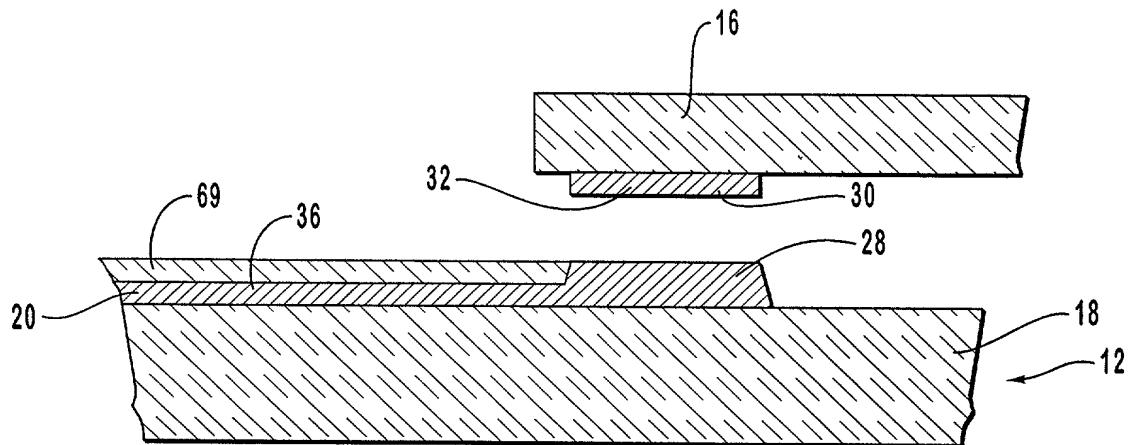


FIG. 8

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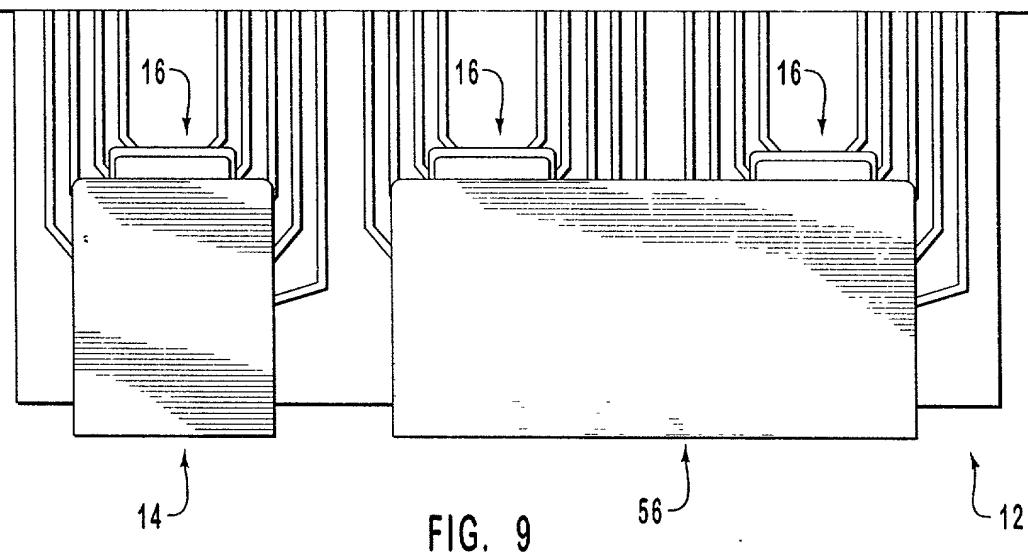


FIG. 9

PATENT APPLICATION
Docket No: 11675.168

DECLARATION, POWER OF ATTORNEY, AND PETITION

I, Leonard E. Mess, declare: that I am a citizen of the United States of America; that my residence and post office address is 4101 Cassia, Boise, Idaho 83705; that I verily believe I am the original, first, and sole inventor of the subject matter of the invention or discovery entitled THERMALLY CONDUCTIVE INTERPOSER AND METHOD OF USE, for which a patent is sought and which is described and claimed in the specification attached hereto; that I have reviewed and understand the contents of the above-identified specification, including the claims; and that I acknowledge the duty to disclose information which is material to the examination of this application in accordance with Section 1.56(a) of Title 37 of the Code of Federal Regulations.

I declare further that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful, false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful, false statements may jeopardize the validity of the application or any patent issuing thereon.

I hereby appoint as my attorneys and/or patent agents: RICK D. NYDEGGER, Registration No. 28,651; DAVID O. SEELEY, Registration No. 30,148; JONATHAN W. RICHARDS, Registration No. 29,843; JOHN C. STRINGHAM, Registration No. 40,831; MICHAEL F. KRIEGER, Registration No. 35,232; BRADLEY K. DeSANDRO, Registration No. 34,521; JOHN M. GUYNN, Registration No. 36,153; GREGORY M. TAYLOR, Registration No. 34,263; DANA L. TANGREN, Registration No. 37,246; ERIC L. MASCHOFF, Registration No. 36,596; KEVIN

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All correspondence and telephonic communications should be directed to:

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Salt Lake City, Utah 84111

Wherefore, I pray that Letters Patent be granted to me for the invention or discovery described and claimed in the foregoing specification and claims, declaration, power of attorney, and this petition.

Signed at Boise, Idaho, this 20 day of
July, 1998.

Inventor: Leonard E. Mess
Leonard E. Mess
4101 Cassia
Boise, Idaho 83705

PATENT APPLICATION
Docket: 11675.168.1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Leonard E. Mess

Serial No.: Not Yet Assigned

Filed: February 9, 2000

For: SYSTEM FOR TESTING A SEMICONDUCTOR
DEVICE

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ASSOCIATE POWER OF ATTORNEY

The Honorable Commissioner of Patents
and Trademarks
Washington, D. C. 20231

Sir:

Please recognize CHARLES L. ROBERTS, Reg. No. 32,434; DAVID L. GRIFFIN, Registration No. P-44,136; R. BURNS ISRAELSEN, Registration No. 42,685; DAVID R. TODD, Registration No. 41,348; JESÚS JUANÓS i TIMONEDA, Registration NO. 43,332; STEPHEN D. PRODNUK, Registration No. 43,020, R. PARRISH FREEMAN, Registration No. 42,556, ADRIAN J. LEE, Registration No. 42,785, and KYLE H. FLINDT, Registration No. 42,539 as associate attorneys for me in the above-entitled application. Please address all future written and telephonic communications to:

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Dated this 9 day of February 2000.

Respectfully submitted,



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